

Form PTO-1449

Docket Number 356952000304

Application Number 09/928,194

INFORMATION DISCLOSURE CITATION
IN AN APPLICATION

Applicant

K. E. PETERSON et al.

Filing Date August 17, 2001

Group Art Unit To Be Assigned

Mailing Date

September 14, 2001

(Use several sheets if necessary)

U.S. PATENT DOCUMENTS

Examiner Initials	Ref. No.	Date	Document No.	Name	Class	Subclass	Filing Date If Appropriate
DM	1.	03/1988	4,730,496	Knecht et al.			
DM	2.	10/1991	5,060,526	Barth et al.			
DM	3.	07/1992	5,132,658	Dauenhauer et al.			
DM	4.	09/1992	5,142,781	Mettner et al.			
DM	5.	01/1993	5,179,499	MacDonald et al.			
DM	6.	03/1993	5,198,390	MacDonald et al.			
DM	7.	08/1993	5,235,187	Arney et al.			
DM	8.	08/1993	5,238,223	Mettner et al.			
DM	9.	02/1994	5,285,097	Hirai			
DM	10.	02/1994	5,287,082	Arney et al.			
DM	11.	05/1994	5,316,979	MacDonald et al.			
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DM	13.	12/1994	5,375,033	MacDonald			
DM	14.	01/1995	5,386,142	Kurtz et al.			
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DM	24.	10/1996	5,567,880	Yokota et al.			

EXAMINER:

Donghee Kang

DATE CONSIDERED:

8-28-01

EXAMINER: Initial if citation considered, whether or not the citation conforms with MPEP 609. Draw a line through the citation if not in conformance and not considered. Include a copy of this form with next communication to applicant.

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25.	12/1996	5,587,601	Kurtz			
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Examiner Initials	Ref. No.	Date	Document No.	Country	Class	Subclass	Translation YES NO	
h m	32.	5/1990	0 368 446	EPO				
h m	33.	3/1994	0588371	EPO				
h m	34.	4/1994	0591554	EPO				
h m	35.	7/1994	0 605 300	EPO				
h m	36.	8/1994	94/18697	PCT				
h m	37.	3/1996	96/08036	PCT				
h m	38.	1/1997	97/01221	PCT				
h m	39.	2/1997	97/04283	PCT				
h m	40.	12/8/94	94/28427	PCT				
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Examiner Initials	Ref. No.	Title
h m	42.	V. A. Yunkin et al., "Highly Anisotropic Selective Reactive Ion Etching of Deep Trenches in Silicon", Elsevier Science B. V., Microelectronic Engineering, vol. 23 (1994) pp. 373-376.
h m	43.	Ammar, Elie S. and Rodgers, T.J., "UMOS Transistors on (110) Silicon", <u>IEEE Transactions on Electron Devices</u> , Vol. Ed-27, No. 5 (1980)
h m	44.	Goodenough, Frank, "Redesigned Surface-Micromachined Accelerometer IC Provides Increased

EXAMINER:

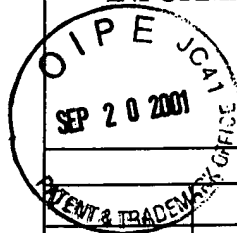
Donghee Kang

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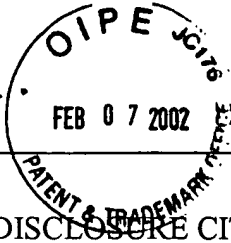
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		Sensitivity of ± 1 -5 G Full Scale", <u>Electronic Design, Technology Advances</u> (1995) pgs. 37, 40
nhc	45.	Sherman, S.J. et al., "A Low Cost Monolithic Accelerometer; Product/Technology Update", <u>IEEE Technical Digest</u> , (1992) pgs. 501-504
nm	46.	PCT Written Opinion dated 2/20/97 which relates to International Application No. PCT/US96/07605 which corresponds to U.S. Application Serial No. 08/449,140
nhc	47.	Y. Uenishi et al., "Micro-Opto-Mechanical Devices Fabricated By Anisotropic Etching of (110) Silicon," Proceedings of the IEEE, Micro Electro Mechanical Systems, 1994, pp. 319-324.
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nhc	51.	K. Petersen et al., "Surface Micromachined Structures Fabricated with Silicon Fusion Bonding", IEEE, 1991, pp. 397-399.
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Sheet 1 of 1

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INFORMATION DISCLOSURE CITATION
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(Use several sheets if necessary)

Applicant

Kurt E. PETERSEN et al.

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U.S. PATENT DOCUMENTS

Examiner Initials	Ref. No.	Date	Document No.	Name	Class	Subclass	Filing Date If Appropriate
hr	1.	2/17/98	5,719,073A	Shaw et al.			
hr	2.	7/4/00	6,084,257A	Petersen et al.			
hr	3.	11/13/01	6,316,796B1	Petersen et al.			

FOREIGN PATENT DOCUMENTS

Examiner Initials	Ref. No.	Date	Document No.	Country	Class	Subclass	Translation YES NO

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(including author, title, Date, Pertinent Pages, Etc.)

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